

Product Datasheet

Rudolph Technologies Metapulse 200

Type	Description
Wafer Diameter	200 mm
Vendor Tool Serial #	1-06-MPO-1033-BR-01
Year of Manufacture	1998
Process	Wafer Inspection
OEM	Rudolph Technologies
Tool Model	Metapulse 200

Configuration

Description

Pattern Recognition
200 mm ergonomic cassette-tilt loaders
Pulse Wafer Transport System
200 mm chuck
200 mm wafer probe
200mm linear positioning stage
Ultrafast 800 nm laser
Programmable motion controller
Color printer (cleanroom approved)
266 MHz Pentium II Motherboard
2GB hard drive
CD ROM drive
LCD screen
Keyboard and Trackball
GEM compliant SECS-II









RUDOLPH
Technologies, Inc.

VANGUARD Series

Serial Number

1-06-MPO-1033-BR-01

Covered Under the Following
US Patent No. 4,710,030
Additional Patent(s) Pending

This instrument Complies with
Performance standards
Specified by federal regulation
21CFR1040.10

Model **MetaPulse®**

Electrical Ratings **4900va** **16Fla** **220vac 1 phase 50/60hz**

Maximum Single Load **5 amps at 220vac**

Main Breaker **10,000 AIC RMS** Mfg. Date **11/98**

Manufactured by
Rudolph Technologies
One Rudolph Road, Flanders, N.J.